Advanced Evaluation of Sub-nm Surface Roughness using Electron Diffraction

R. M. Tumbelaka[A], Y. Kitagawa[A], Juharni[A], Y. Ida[A], Y. Kimoto[A], K. Tsubosaki[A],
A. N. Hattori[B], H. Momono[C], and K. Hattori[A]
[A]Nara Inst. Sci. Technol., [B]SANKEN, Osaka Univ., [C]Yonago College

FIGURES:

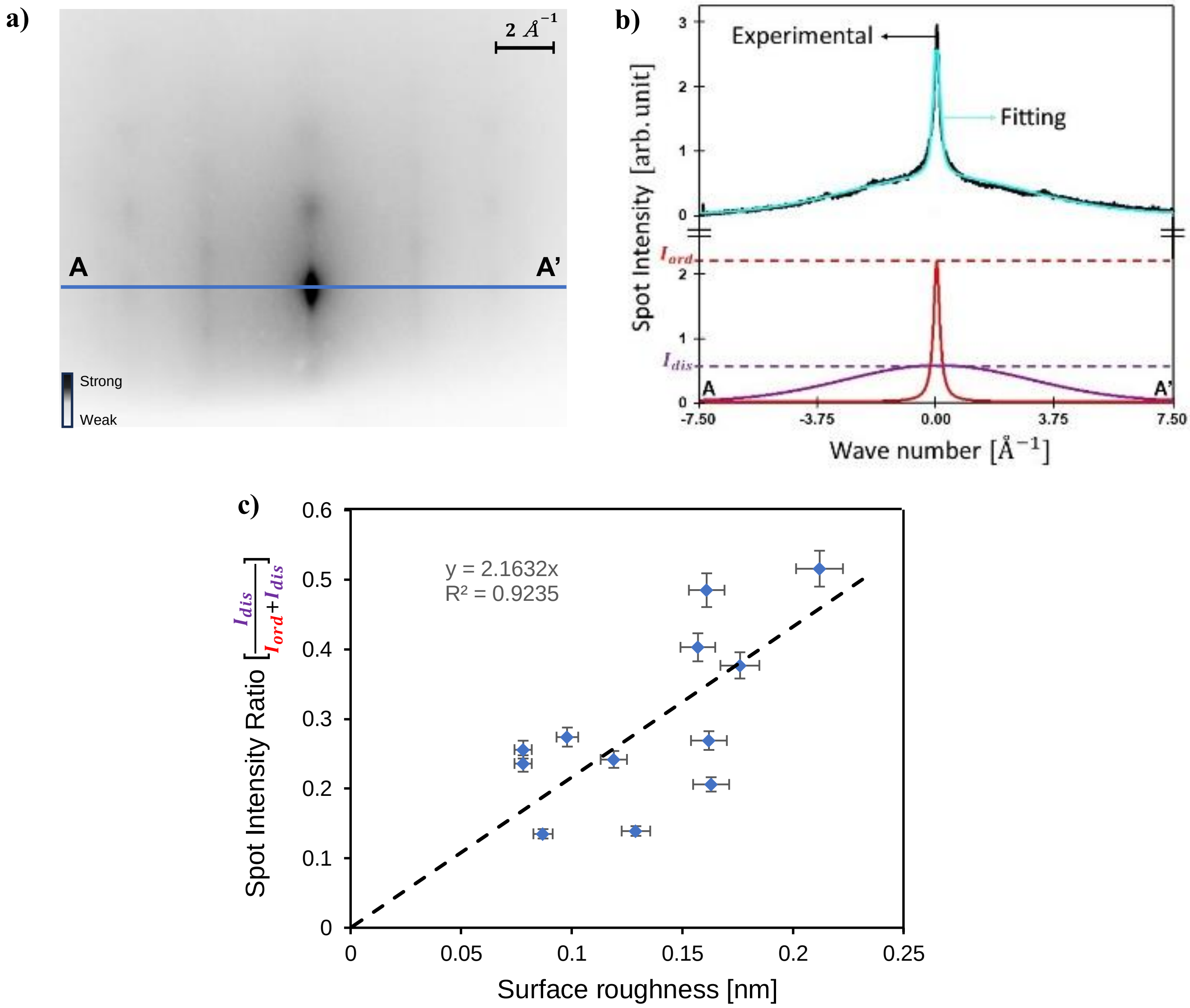

Fig. 1. (a) A standard RHEED pattern obtained from an HOPG surface exhibiting a roughness of 0.163 nm. (b) Fitting of 006 diffraction spot intensity profile at A-A' in (a) with sharpen and broad peaks with intensities, I_{ord} and I_{dis}, respectively (c) Corelation between the spot intensity ratio and surface roughness.